### **Lehigh University Lehigh Preserve**

17th University Glass Conference

Glass Conferences and Workshops

Summer 6-26-2005

XVI, Part 2: Preparation Of Thin Films Of Complex Composition By Pulsed Laser Deposition- A Way for Producing New Amorphous Materials Applicable in Optoelectronics, Chemistry and Biology

Miloslav Frumar University Pardubice

Follow this and additional works at: https://preserve.lehigh.edu/imi-tllconferences-17thuniversityglassconference



Part of the Materials Science and Engineering Commons

### Recommended Citation

Frumar, Miloslav, "XVI, Part 2: Preparation Of Thin Films Of Complex Composition By Pulsed Laser Deposition- A Way for Producing New Amorphous Materials Applicable in Optoelectronics, Chemistry and Biology" (2005). 17th University Glass Conference. 22.

https://preserve.lehigh.edu/imi-tll-conferences-17thuniversityglassconference/22

This Video is brought to you for free and open access by the Glass Conferences and Workshops at Lehigh Preserve. It has been accepted for inclusion in 17th University Glass Conference by an authorized administrator of Lehigh Preserve. For more information, please contact preserve@lehigh.edu.

# New amorphous materials with applications in optics, optoelectronics, chemistry, medicine and biology prepared by pulsed laser deposition

M. Frumar a,b, B. Frumarovac, P. Nemeca,b, T. Wagnera,b and M. Hrdlickaa

aDep. of General and Inorganic Chemistry, University of Pardubice,
 bResearch Centre of the University of Pardubice,
 cJoint Lab. of Solid State Chemistry of Inst. Macromol. Chemistry
 Czech Acad. Sci. and of Univ. Pardubice, Pardubice,
 Czech Republic

### Introduction

Chalcogenide glasses and films in focus of many labs:-many present and potential applications, e.g.:

- optical IR elements and memories, filters, holography
- fibers, photoresists, lasers, gratings, waveguides, amplifiers, ...
- planar devices, optical circuits, optical signal processing,
- ionic and optical sensors, microbateries,
- -X-ray sensors, analysers, etc.

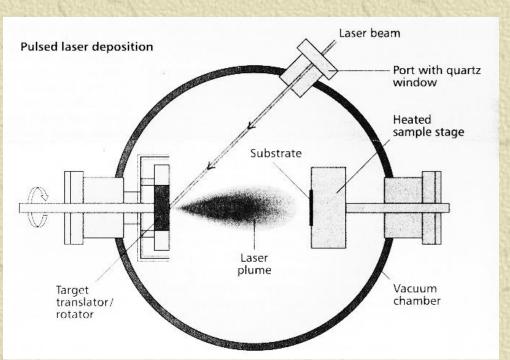
Many systems studied, mostly sulfides, selenides, recently also tellurides, e. g. GeTe, Ge-Sb-Te, .... and others:

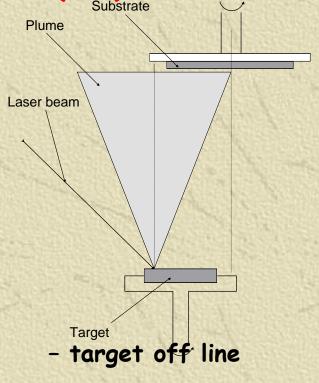
search for <u>new materials</u>, <u>new properties</u> and <u>new effects</u> (e.g. for optical storage, optical signal processing, multilevel optical and electrical storage, biology, medicine, ...)

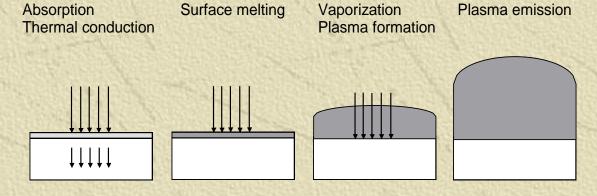
thin films, binary, ternary or multinary systems, no optimal:

- preparation, properties, applications, performance
- often difficulties in preparation of thin films, especially binary, ternary, multinary, with different volatility =>

A possible solution: pulsed laser deposition (PLD) Substrate







short pulses (ns or fs) of high intensity and energy  $\sim 10^8$  –  $10^9$  W/cm² (for ns, for fs much higher, up to  $10^{16}$  W/cm²) in UV, VIS or IR region,

our: 248nm, hv = 5 eV, 480 kJ/mol > chemical bonds energies: evaporation, atomization, formation of ionized plume

- vapors in plume are very hot (~X.10<sup>3</sup>K, dissociation?, new compounds are formed in hot plasma,
- quenched quickly by condensation,
- the obtained films far from equilibrium
- many materials, e.g. multinary compounds with different volatility components. Every pulse evaporates all components, independently on their vapor pressure.
- films of unusual composition, e.g. Ga-La-S, PbS-AgI-As-S, Tl-Ag-As-I-S, can be prepared (mostly amorphous).

- the parameters of pulses (e.g. energy, frequency and number) can be controlled; the properties of films and their stoichiometry can be controlled as well.

The mechanism of evaporation and film formation is complex:

- exfoliation
- •fragmentation (the energy of fragmentation: much lower than E of evaporation
- \*surface or subsurface evaporation
- surface melting
- •bubles formation
- \*phase explosion (from superheated liquids).
- particulates formation,
- plume formation

- · dissociation, atomization, plasma formation and ionization (e.g. e-, ions, unusual states, e.g.  $Cu^{5+}$ ,  $Cu^{4+}$ ,  $Cu^{3+}$  were found)
- vapors condensation, their interaction, film formation and relaxation, self-annealing

The kinetic energy (temperature) of the particles in the plume is high (up to keV)  $\Rightarrow$ 

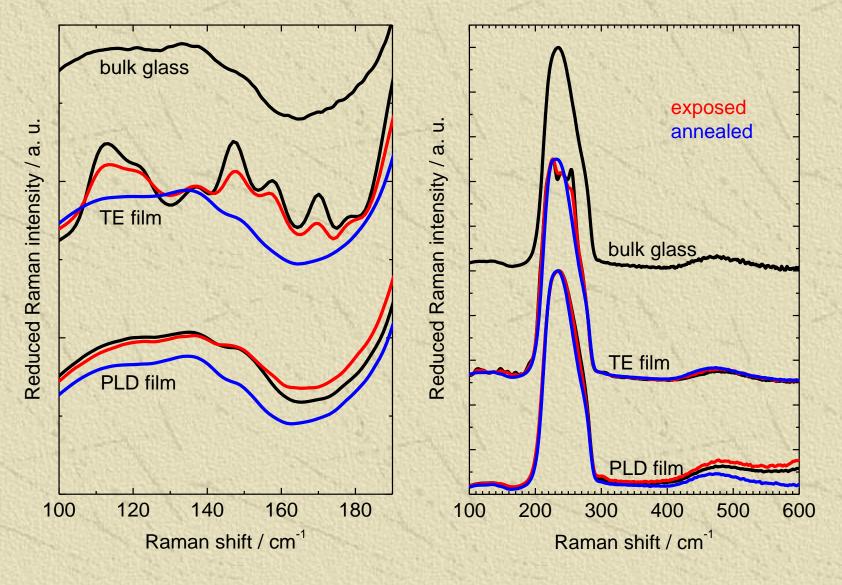
chemical reactions among particles (fragments) during or after condensation are quicker (easier, self-annealing)  $\Rightarrow$  the structure of some ablated films can be closer to the structure of target glass - contrary to films prepared by thermal evaporation (TE).

Sometimes <u>higly oversaturated films with unusual composition</u> and <u>properties are obtained</u>, e.g. As-rich As-Se system

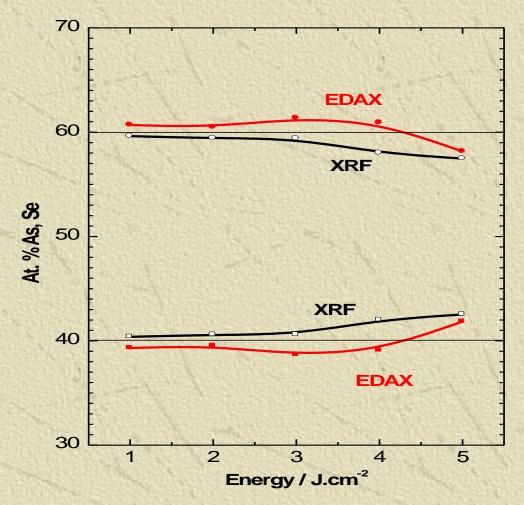
### In some cases, e.g. in As-S system:

- a) the fragments in the plume have different rates of condensation- new compounds are formed in the hot plasma → composition change
- b) the structure is different from thermally evap. films (TE)

  In this paper: ablated films
- As-S, As-Se, Ge-Se, Ge-Ga-Se and RE doped systems
- tellurides of eutectic compositions (Sn-Te, In-Te, Sb-Te)
- other systems, e.g. Ag-As-S, Ag-Sb-S and As-In-S:Sm



Raman spectra of bulk As2Se3 glass and As-Se thin films



Composition of As-Se thin films prepared by PLD on energy density of the laser beam: full squares - As content from EDAX, open squares - As content from XRF, full circles - Se content from EDAX, open circles - Se content from XRF;

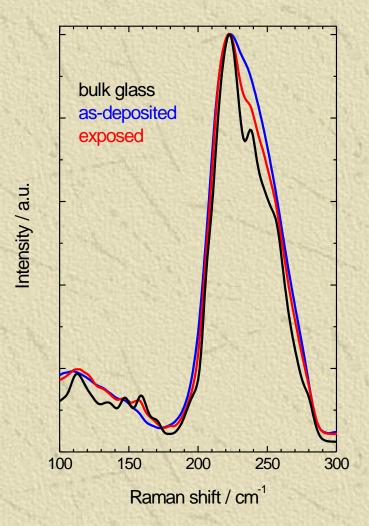
The <u>PLD  $As_2Se_3$ </u> films contain (in comparison with TE films) <u>less 'wrong' As-As and Se-Se bonds</u> and less  $As_4Se_4$ ,  $As_4Se_3$ ,  $Se_8$  or  $Se_n$  particles.

- High kinetic energy of plasma-plume particles enables their interaction  $\Rightarrow$  (Eqs. 1-3), densities of  $As_4Se_4$ ,  $As_4Se_3$ ,  $Se_n$  are lowered, e.g.

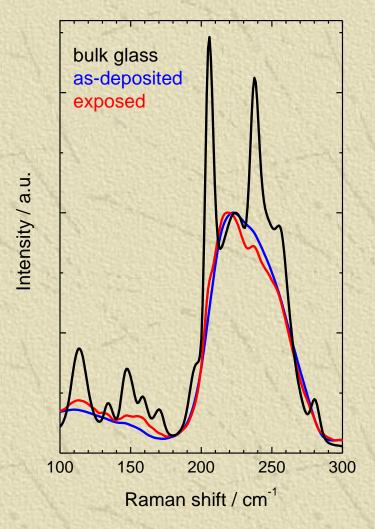
$$As_4Se_4 + (2/n) Se_n = 2 As_2Se_3$$
 (1)

$$As_4Se_3 + (3/n) Se_n = 2 As_2Se_3,$$
 (2)  
or just

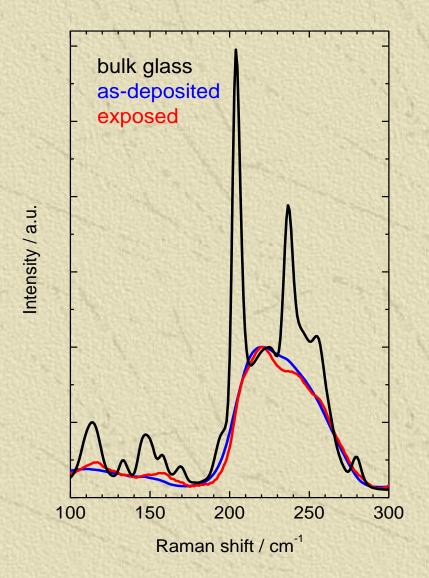
$$|As-As| + |Se-Se| = 2|As-Se|$$
 (3)



Raman spectra of bulk As<sub>50</sub>Se<sub>50</sub> glass (full line), as-deposited (dashed line), and exposed (dotted line) PLD As<sub>50</sub>Se<sub>50</sub> thin films



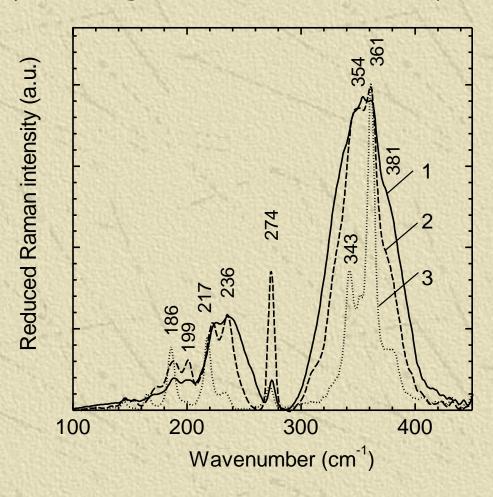
Raman spectra of bulk  $As_{57.14}Se_{42.86}$  ( $As_4Se_3$ ) glass (full line), asdeposited (dashed line), and exposed (dotted line) PLD  $As_4Se_3$  thin films



Raman spectra of bulk  $As_{60}Se_{40}$  glass (full line), as-deposited (dashed line), and exposed (dotted line) PLD  $As_{60}Se_{40}$  thin films

## In As-S system: thermal dissociation $2As_2S_3 = As_4S_4 + S_2 \Rightarrow$ change of composition

para-realgar, As<sub>4</sub>S<sub>4</sub>, is formed only at high temperatures

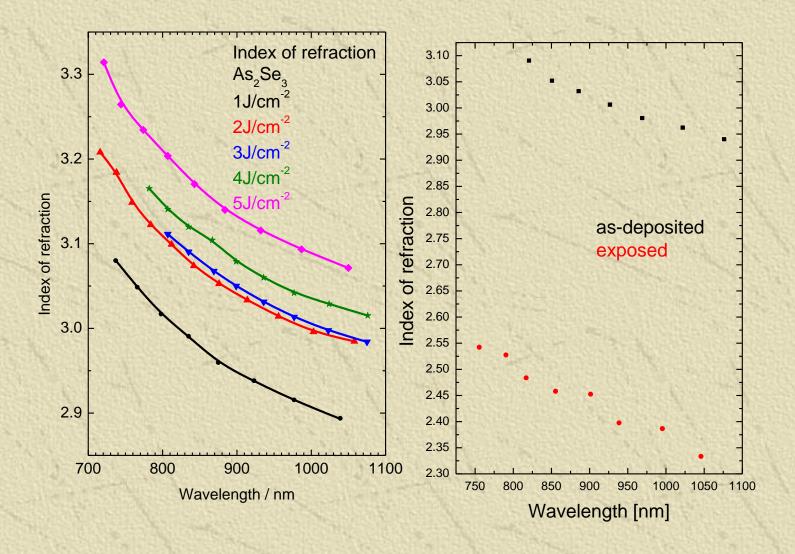


As<sub>50</sub>S<sub>50</sub> from As<sub>2</sub>S<sub>3</sub>

1 as-evaporated

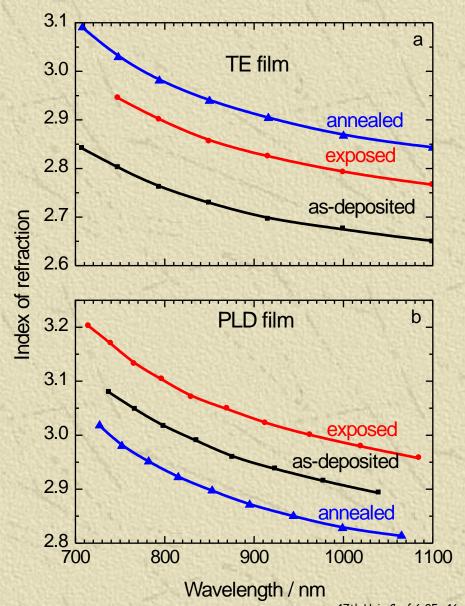
2 exposed

3 annealled



Spectral dependence of index of refraction values for  $As_4Se_3$  PLD thin films

Index of refraction, n, of As<sub>2</sub>Se<sub>3</sub> is different from bulk glasses PLD and TE films, An can be much larger



### In PLD films:

index of refraction: the exposure increases, - following annealing - decreases

probably by densification, microliquation, formation of nanoparticles?, photolysis, phase separation and thermally-induced expansion of the amorphous layers.

The values of n are significantly higher in PLD films in comparison with TE films-

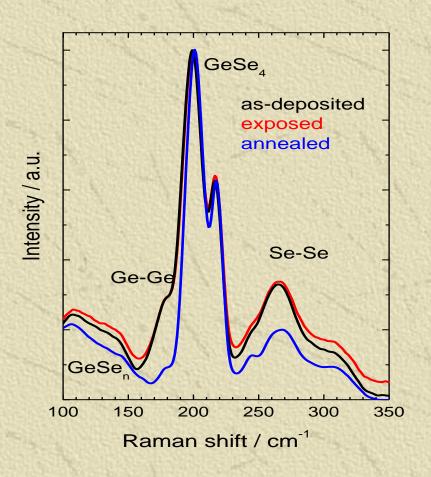
The values of third-order non-linear susceptibility, in PLD films also higher.

$$\chi^{(3)} = \frac{A}{(4\pi)^4} \left(\frac{E_d}{E_0}\right)^4 = \frac{A}{(4\pi)^4} \left(n_0^2 - 1\right)^4 \tag{4}$$

In Ge, Se1-x:

exposure and annealing - decrease of the density of Ge-Ge and Se-Se bonds in  $Ge_2(Se_{1/2})_6$  structural units

$$|Ge - Ge| + |Se - Se| \leftrightarrow 2|Ge - Se|$$
 (5)



Raman spectra  $Ge_{\times}Se_{1-\times}$ , x = 0.24 thin films

A broad Raman band 100-150 cm<sup>-1</sup> - vibrations of structural units similar to the GeSe formed  $T > 500^{\circ}C$ ).

By annealing – decrease of Raman bands of Ge-Ge and Se-Se bonds  $\rightarrow$  more chemically ordered system  $\rightarrow$  higher  $E_a$ 

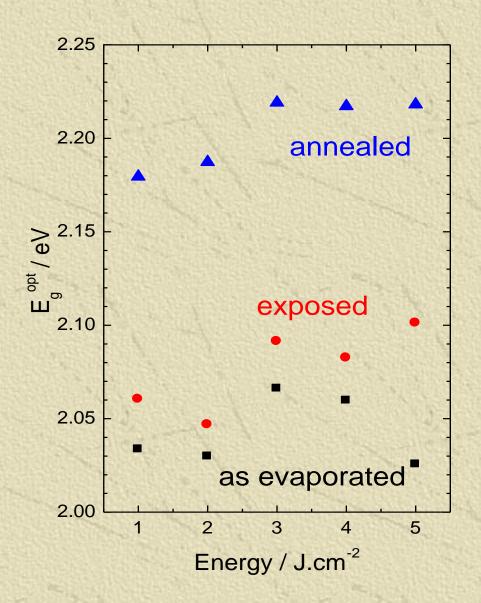
$$xGeSe_{2(s)} \leftrightarrow (x-y) GeSe_{2(g)} + y GeSe_{(g)} + y/n Se_{n(g)},$$
 (6)

At T > 500°C, GeSe become Se deficient (Chizhikov and Schastlivyi 1964):

$$mGeSe_{(g)} \leftrightarrow mGeSe_{1-p} + (p/n)Se_n$$
 (7)

Due to high energy of the particles (GeSe<sub>2</sub>, GeSe, GeSe<sub>1-p</sub>, Se<sub>n</sub>, and other fragments of GeSe<sub>2</sub>) in the plume,

some react together when deposited, (reactions (2) and (3) in the backward direction).



Egopt, Ge28Se72

Slight photobleaching, larger bleaching by annealing

By annealing- decrease of Raman bands of Ge-Ge and Se-Se bonds  $\rightarrow$  more chemically ordered system  $\rightarrow$  higher  $E_g$ 

### <u>Eutectic tellurides - optical and electrical memories</u> Melting, crystallization, composition is not changed

### In this paper:

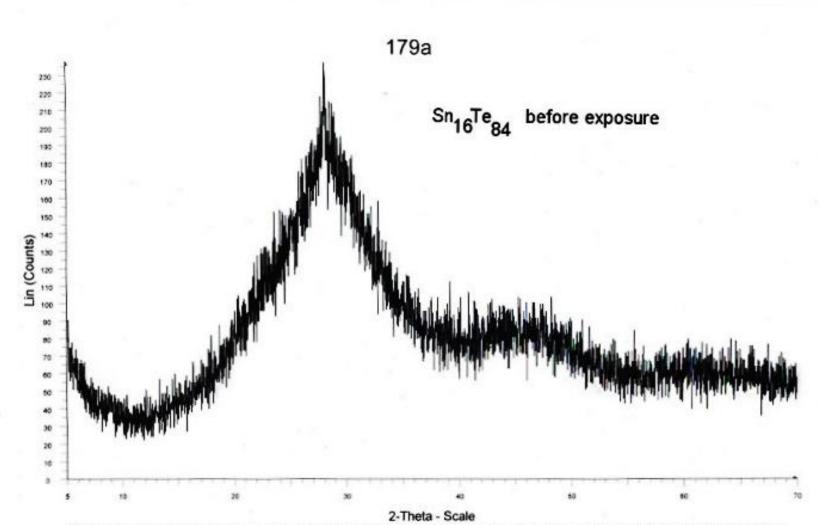
 $Sn_{16}Te_{84}$ ,  $In_{13}Te_{87}$ ,  $Sb_{11}Te_{89}$ .

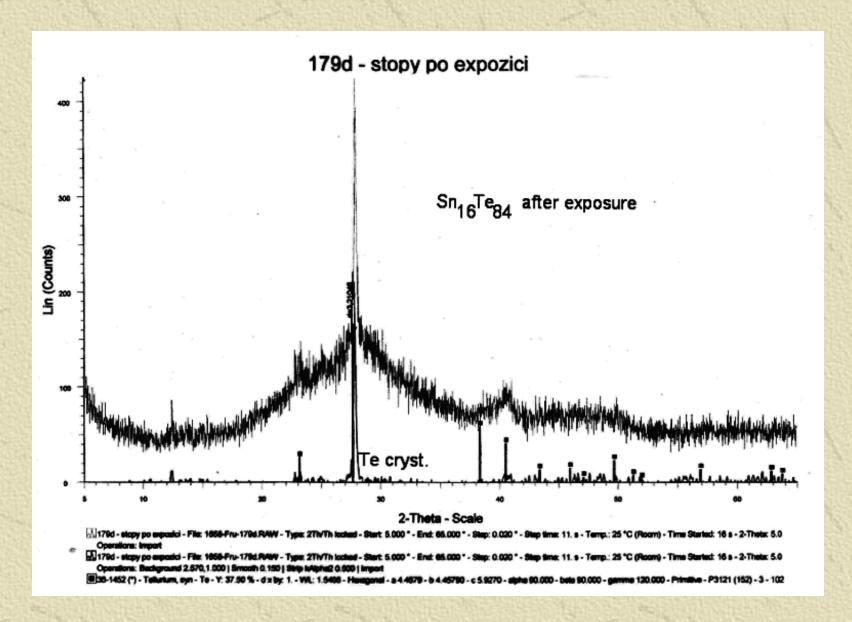
Melting  $t \cong 400-420^{\circ}C$ 

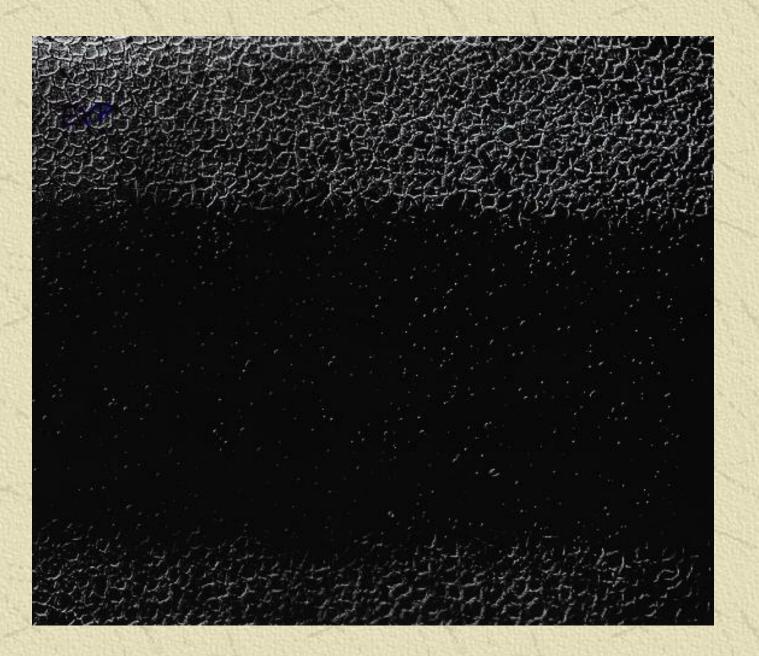
Bulk samples- <u>crystalline</u> ablated films - <u>amorphous</u>, <u>good optical transmittance up to 18</u>  $\mu$ m, untill now- many droplets

Exposure high pressure Hg lamp (~14mW/cm²) -nearly no changes

Excimer laser pulses - <u>crystallization</u>, <u>prevailing Te crystals</u> the Raman spectra of very low intensity, only small changes







Sn<sub>16</sub>Te<sub>84</sub>

### Conclusion

1. The films prepared by PLD are often of different structure (x TE films) and different properties. Thin films of unusual or complex composition and properties can be prepared.

2. The volatile and non-volatile parts of target material can be deposited at once.

3. Many materials (e.g. tellurides) can be newly prepared as amorphous due to quenching from high temperatures. Their physics and chemistry is mostly unknown. Properties are promissing.

- 5. The photoinduced effects are different in some cases higher changes of n, T, R, E<sub>g</sub><sup>opt</sup>
  Higher changes of n higher nonlinearity
- 6. Due to higher index of refraction and larger photoinduced changes of structure and properties, the PLD prepared chalcogenide films
  - materials for waveguides, optical signal processing, memories, .... and for other applications.

7. High ionic conductivity, Ag doped and other complex systems - ionic sensors, artificial tongue

# Acknowledgements

The support of Ministry of Education of the Czech Republic under the projects LC 523, 002167501, and GA CR 203/05/0524 are highly acknowledged.

# Thank you for your kind invitation and for your attention